

RESOURCE CONSUMPTION CALCULATOR

Abstract of the Disclosure

A process tool controller of a semiconductor processing tool is provided with software that enables collecting, monitoring and logging information regarding the tool's consumption. Data is collected from the devices used for control of process conditions via the analog and digital inputs and outputs of the process tool controller. Consequently, the devices for controlling the process conditions have the additional function of measuring the tool's consumption. In this way the information regarding the tool's consumption is completely collected on board of the process tool. The parameters to be monitored and reported can be configured by the user, with use of a configuration editor, resulting in optimum flexibility of the system. In the illustrated embodiment, the user interface of the consumption monitoring and logging software is integrated into the user interface of the process control and monitoring software. The information regarding the tool's consumption can be communicated to a supervisor computer via a network.

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